IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:

Applicants: KING, Mackenzie, et al.

Application No.: 10/722.174

Art Unit: 1742

Date Filed: November 25, 2003 Examiner: Nicholas A. Smith

Title: ON-WAFER Customer No.:

ELECTROCHEMICAL
DEPOSITION PLATING
METROLOGY PROCESS
AND APPARATUS

23448

CERTIFICATE OF EFS FILING

Thereby certify that this document is being filed via EFS in the United States Patent and Trademark Office on March 10, 2008.

/Steven J. Hultquist/

RESPONSE TO NOVEMBER 9, 2007 FINAL OFFICE ACTION IN U.S. PATENT APPLICATION NO. 10/722,174; AND PETITION FOR ONE MONTH EXTENSION OF TIME

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Sir

This responds to the November 9, 2007 Office Action in the above-identified application. A petition for one month extension of time is hereby requested under the provisions of 37 CFR 1.136, extending the period for reply to the Office Action from February 9, 2008 to March 10, 2008. The fee specified in 37 CFR 1.17(a)(2) for such extension of time is being paid by on-line payment at the time of EFS filing of this response.

A listing of the claims of the above-identified patent application are set out in Section I (Listing of the Claims) hereof.

Remarks concerning the substance of the November 9, 2007 Office Action and patentable distinction of the pending claims are set out in **Section II** (Remarks) hereof.